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PATENT
8007-1111

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicants: Atsushi SAKURAI et al. Confirmation: 1454
Serial No.: 10/583,942 Art Unit: Not assigned
Filed: June 22, 2006 Examiner: Not assigned
For: METAL COMPOUND, MATERIAL FOR THIN FILM
FORMATION, AND PROCESS OF FORMING THIN FILM

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents **September 22, 2006**
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the references listed on the accompanying Form PTO-1449 are hereby made of record in the above-identified application. These documents are cited in the present specification or correspond to a reference cited in the specification. The discussion in the specification, together with the enclosed English language abstracts, constitutes a concise explanation of the relevance of the foreign references.

This Information Disclosure Statement is being submitted within three months of the filing date of this application; therefore, no fee is required.

Respectfully submitted,
YOUNG & THOMPSON

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(Use several sheets if necessary)

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10/583,942

Applicant:
Atsushi SAKURAI et al.

Filing Date:
June 22, 2006

Group Art Unit:
Not assigned

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Inorganic Chemistry, Vol. 29, No. 23, 1990, pp. 4640-4646.

EXAMINER:

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

* English language abstract provided for the Examiner's convenience

BC:rk